

L Number	Hits	Search Text	DB	Time stamp
-	109	piezoelectric and ((top and bottom) adj electrode\$1).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/17 17:40
-	44	piezoelectric and ((top and bottom) adj electrode\$1) and taper\$4	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/17 17:47
-	603	piezoelectric and ((top and bottom) adj electrode\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/17 16:47
-	4507	(Al or aluminum) and taper\$4 and (Ti or titanium) and etch\$3 and (mask\$3 or \$5resist)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/17 16:25
-	2895	(Al or aluminum) and taper\$4 and (Ti or titanium) and etch\$3 and (mask\$3 or \$5resist) and electrod\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/17 16:24
-	823	(Al or aluminum) and taper\$4 and (Ti or titanium) and (etch\$3 adj rate\$1) and (mask\$3 or \$5resist) and electrod\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/19 15:32
-	21	((Al or aluminum) and taper\$4 and (Ti or titanium) and etch\$3 and (mask\$3 or \$5resist)).ab.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/17 16:26
-	193	etch\$3 and ((top and bottom) adj electrode\$1) and taper\$4	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/17 16:27
-	404	(aluminum with taper\$2) and etch\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/17 16:48
-	224	(aluminum with taper\$2) same etch\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/17 16:48
-	0	1151236.URPN.	USPAT	2003/11/17 16:56
-	9	((Al or aluminum) and taper\$4 and (Ti or titanium) and (etch\$3 adj rate\$1) and (mask\$3 or \$5resist)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/17 16:57
-	11	5464500.URPN.	USPAT	2003/11/17 16:59
-	5	("3700508" "3825454" "4610502" "5007984" "5118385").PN.	USPAT	2003/11/17 17:00
-	5	("3700508" "3825454" "4610502" "5007984" "5118385").PN.	USPAT	2003/11/17 17:05
-	11	5464500.URPN.	USPAT	2003/11/17 17:05
-	47	((Al or aluminum) and taper\$4 and (Ti or titanium) and etch\$3 and (mask\$3 or \$5resist)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/17 17:07

	2	("5575962").PN.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:15
	456	(438/738).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:37
	174	((438/738).CCLS.) and (al or aluminum) and (ti or titanium)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:34
	23	((438/738).CCLS.) and (al or aluminum) and (ti or titanium) and taper\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:36
	134	(216/95).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:36
	3	((216/95).CCLS.) and (al or aluminum) and (ti or titanium) and taper\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:36
	178	(438/735).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:37
	141	(438/736).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:38
	121	(438/737).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:38
	201	(438/739).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:38
	219	(438/742).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:38
	754	(216/2).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:38
	1106	(216/13).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:39
	115	(216/32).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:39

	1063	(216/41).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:39
	75	piezoelectric and aluminum and ((top and bottom) adj electrode\$1).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:40
	143	aluminum and ((top and bottom) adj electrode\$1) and taper\$4	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:42
	1066	piezoelectric and aluminum and electrode\$1 and taper\$4	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:52
	4	(piezoelectric and aluminum and electrode\$1 and taper\$4).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:49
	27	(piezoelectric and aluminum and electrode\$1).clm. and taper\$4	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:51
	735	piezoelectric and aluminum and electrode\$1 and (resonator\$3 or transducer\$1).ti.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 17:58
	4	(piezoelectric and aluminum and electrode\$1 and taper\$3).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 18:00
	356	(piezoelectric and aluminum and electrode\$1).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 18:01
	1045	(aluminum and ((aluminum adj nitride) or (zinc adj oxide)) and electrode\$1).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 18:02
	14	(aluminum and taper\$3 and ((aluminum adj nitride) or (zinc adj oxide)) and electrode\$1).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 18:04
	120	(TFR or TFT) and (aluminum and ((aluminum adj nitride) or (zinc adj oxide)) and electrode\$1).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 18:09
	17	((thin adj film adj resonator) or TFR).ab. and (aluminum and ((aluminum adj nitride) or (zinc adj oxide)) and electrode\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 18:11
	157	((thin adj film adj resonator) or TFR).ti.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/17 18:11

	526	((TFR) or (thin-film adj resonator\$1) or (film adj resonator\$1)) and ((zinc adj oxide) or (aluminum adj nitride) or AlN or ZnO)) or (((TFR) or (thin-film adj resonator\$1) or (film adj resonator\$1)).ti.) or (((TFR) or (thin-film adj resonator\$1) or (film adj resonator\$1)).ab.) or (((TFR) or (thin-film adj resonator\$1) or (film adj resonator\$1)).clm.)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/17 19:02
	496	((TFR) or (thin-film adj resonator\$1) or (film adj resonator\$1)) and (electrode\$1 or aluminum)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/17 19:01
	723	((TFR) or (thin-film adj resonator\$1) or (film adj resonator\$1)) and ((zinc adj oxide) or (aluminum adj nitride) or AlN or ZnO)) or (((TFR) or (thin-film adj resonator\$1) or (film adj resonator\$1)).ti.) or (((TFR) or (thin-film adj resonator\$1) or (film adj resonator\$1)).ab.) or (((TFR) or (thin-film adj resonator\$1) or (film adj resonator\$1)).clm.) or (((TFR) or (thin-film adj resonator\$1) or (film adj resonator\$1)) and (electrode\$1 or aluminum))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/17 19:02
	395	((TFR) or (thin-film adj resonator\$1) or (film adj resonator\$1)) and ((zinc adj oxide) or (aluminum adj nitride) or AlN or ZnO)) or (((TFR) or (thin-film adj resonator\$1) or (film adj resonator\$1)).ti.) or (((TFR) or (thin-film adj resonator\$1) or (film adj resonator\$1)).ab.) or (((TFR) or (thin-film adj resonator\$1) or (film adj resonator\$1)).clm.) or (((TFR) or (thin-film adj resonator\$1) or (film adj resonator\$1)) and (electrode\$1 or aluminum))	USPAT; US-PGPUB	2003/11/17 19:02
	278	(bulk adj acoustic).ti.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/17 19:09
	57	(bulk adj acoustic).ti. and (electrode\$1 with (aluminum or Al))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/17 19:09
	2	("61077344").PN.	JPO; DERWENT	2003/11/19 15:26
	3817	(etch\$3 and taper\$2).ab.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/19 16:35
	1531	((etch\$3 and taper\$2).ab.) and (mask\$3 or \$5resist) and layer	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/19 15:34
	199	((etch\$3 and taper\$2).ab.) and (mask\$3 or \$5resist) and (second adj (layer or film or metal\$3)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/19 15:39

-	39	(etch\$3 and taper\$2 and (Ti or titanium) and (Al or aluminum)).ab.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/19 16:25
-	1	2002-087381.NRAN.	DERWENT	2003/11/19 15:53
-	673	(etch\$3 and taper\$2 and angle).ab.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/19 16:30
-	53	(etch\$3 and taper\$2 and angle).ab. and (Ti or titanium)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/19 16:30
-	144	(etch\$3 and taper\$2).ab. and (al or aluminum) and (Ti or titanium) and (mask\$3 or \$5resist)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/19 16:36